

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Patent No. .... 7,247,248 B2  
Patent Issue Date..... July 24, 2007  
Application Serial No. ....10/516,927  
Filing Date .....December 1, 2004  
Assignee ..... Sensfab Pte Ltd  
Inventorship ..... Tee et al.  
Attorney's Docket No. .... DR10-006  
Title:.....Method of Forming Atomic Force Microscope Tips

**REQUEST FOR CERTIFICATE OF CORRECTION OF PATENT**  
**FOR PTO MISTAKE (37 C.F.R. 1.322(a))**

To: Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450  
ATTN: Decision and Certificate of Correction  
Branch of the Patent Issue Division  
  
From: Jennifer J. Taylor, Ph.D. (Tel. 509-624-4276; Fax 509-838-3424)  
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Sir/Madam:

It is hereby requested that a Certificate of Correction be issued with respect to Patent No. 7,247,248 B2, granted July 24, 2007, in accordance with the Certificate of Correction form attached hereto.

The error(s) listed on the Certificate of Correction form were apparently incurred through the fault of the PTO as will be disclosed by the records of files in the Office.

Attached hereto is Form PTO-1050 which is suitable for printing.

Since this Certificate of Correction is being requested due to PTO errors, it is believed that no fee is due. However, in the event that a fee is required for issuance of this Certificate of Correction, please charge the fee specified under 37 C.F.R. § 1.20(a) to Deposit Account No. 23-0925. Please credit Deposit Account No. 23-0925 with any overpayment of the above fee.

Respectfully submitted,

Dated: 1/4/2008

By: Jennifer J. Taylor  
Jennifer J. Taylor, Ph.D.  
Reg. No. 48,711

UNITED STATES PATENT AND TRADEMARK OFFICE  
CERTIFICATE OF CORRECTION

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PATENT NO. : 7,247,248 B2

APPLICATION NO.: 10/516,927

DATED : July 24, 2007

INVENTOR(S) : Tee et al.

It is certified that an error or errors appears in the above-identified patent and that said Letters Patent is hereby corrected as shown below:

Column 2, Line 56 – Replace “silicon I” with --silicon 1--.

Column 4, Line 27 – Replace “A method of...” with --A method of forming silicon atomic force microscope tips including the steps of:--.

Column 5, Line 22 – Replace “is and electrochemical” with --is an electrochemical--.

**Mailing Address of Sender:**

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